



THE 58TH INTERNATIONAL CONFERENCE ON ELECTRON, ION, AND PHOTON BEAM TECHNOLOGY AND NANOFABRICATION



The Omni Shoreham Hotel Washington DC, May 27 – 30, 2014

The EIPBN Conference is recognized as the foremost international meeting dedicated to lithographic science and process technology and its use in micro and nanofabrication techniques and their applications. The conference brings together engineers and scientists from industries and universities from all over the world to discuss recent progress and future trends.

Abstracts should be submitted online at www.eipbn.org. Abstracts are limited to one page of text (12 point or larger type) and a second, optional page with up to four figures. Abstract deadline: January 11, 2014

Micrograph Contest: EIPBN offers the opportunity to immortalize your favorite micrograph(s). Categories and previous winners are described on our website.

Limited funds are available to support **student travel**. The Conference Chair must receive a letter requesting support from the student's advisor by April 25, 2014. For helping with housing costs a "Room with another student" option will be available at the Omni Shoreham.

Abstracts representing **high quality original research** are invited in the following areas:

- Nanoimprint lithography
- Directed self-Assembly
- Biologically-inspired assembly
- Atomic and molecular manipulation
- Electron- and ion-beam lithography
- Advanced optical lithography
- Dimensional metrology, alignment
- Imaging methods
- Scanned-probe-based patterning
- Resists and resist processing
- Maskless lithography Extreme
- Soft lithography and embossing
- Extreme UV lithography
- Nanoscale processing techniques

Topics in **emerging technologies** include:

- Simulation and modeling for the nano-scale
- Integrated nano-photonics
- Patterned media and data storage
- Nano-electronics
- Nano-biology
- Micro- and nano-scale MEMS
- Micro- and nano-fluidics
- Nanofabrication for energy sources

Conference Chair

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To add your name to the mailing list, please mail a business card or e-mail to the Conference Chair.

The EIPBN conference is co-sponsored by the American Vacuum Society (www.av.s.org), in cooperation with the IEEE Electron Devices, Lasers and Electro-optics Societies and the Optical Society of America.



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